



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Jing-Chie Lin :
Serial No: 10/673349 : Art Unit #1763
Filed: 30 September 2003 : Examiner: G.A.Goudreau
Title: METHOD FOR USING AMMONIUM FLUORIDE
SOLUTION IN A PHOTOELECTRO-CHEMICAL
ETCHING PROCESS OF A SILICON WAFER

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated 20 July 2004, please amend the above-referenced application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.